**Dong Yan**

**Sr. Development Engineer.**

**Education:**

* Ph. D in Automatic Control Systems and Engineering: June 1995 Beijing University of Aeronautics and Astronautics, Beijing, China

**Experience:**

Dong Yan possess more than 16 years experience in NEMS/MEMS technology development and semiconductor product engineering, at international Nanosciences and Nanoengineering labs and centers.

Before joining CNSE at UC Riverside in 2006, he worked as a Research Associate at the School of Electrical and Computer Engineering, Cornell University, New York, where he conducted research on chip scale atomic clock, radio isotope micropower sources, and infrared imaging projects funded by DARPA. In 1995, Dong Yan started his research in MEMS in the Department of Precision Instruments, at Tsinghua University, China.

Dongâ€™s expertise is in tool operation and process optimization, integration and development, and is experienced at developing new processes for the specific fabrication objectives.

**Research Interests:**

His research interests are in the areas of the design, fabrication and characterization of inertial, optical and microfluidic NEMS/MEMS and BioNEMS/MEMS sensors and devices. Currently, he is focusing on NEMS/MEMS based fabrication and metrologies technologies development.

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